



中华人民共和国国家标准

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表面化学分析 俄歇电子能谱和 X 射线 光电子能谱 横向分辨率、分析面积和 分析器所能检测到的样品面积的测定

Surface chemical analysis—Auger electron spectroscopy and X-ray
photoelectron spectroscopy—Determination of lateral resolution,
analysis area, and sample area viewed by the analyser

(ISO/TR 19319:2003, IDT)

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前 言

本标准依据 GB/T 1.1—2009 和 GB/T 20000.2—2009 给出的规则起草。

本标准使用翻译法等同采用 ISO/TR 19319:2003《表面化学分析 俄歇电子能谱和 X 射线光电子能谱 横向分辨率、分析面积和分析器所能检测到的样品面积的测定》。

本标准由全国微束分析标准化技术委员会(SAC/TC 38)提出并归口。

本标准负责起草单位:厦门爱劳德光电有限公司、清华大学化学系、中国科学院化学所。

本标准起草人:王水菊、岑丹霞、姚文清、李展平、刘芬。

引 言

本标准适用于以下四个方面：

- a) 提供测定俄歇电子能谱和 X 射线光电子能谱横向分辨率的指导,这里测量的是与样品表面上的位置相关联的俄歇电子或 X 射线光电子的峰强度。
- b) 提供在俄歇电子能谱和 X 射线光电子能谱的应用中测定分析面积的指导。
- c) 提供在俄歇电子能谱和 X 射线光电子能谱的应用中测定分析器所能检测到的样品面积的指导。
- d) 为制定测量俄歇电子能谱和 X 射线光电子能谱的横向分辨率、分析面积和分析器所能检测到的样品面积的新国际标准和国家标准提供基础。

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